

<b>Notice of References Cited</b>		Application/Control No. 10/810,106	Applicant(s)/Patent Under Reexamination YANG ET AL.	
		Examiner BRET CHEN	Art Unit 1792	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,003,526	12-1999	Lo et al.	134/1.1
*	B	US-6,176,936	01-2001	Taguwa, Tetsuya	134/2
*	C	US-6,863,019	03-2005	Shamouilian et al.	118/723R
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Uchida, K., "Novel chamber cleaning method using atomic hydrogen generated by hot catalyzer". Thin Solid Films □□Volume 395, Issues 1-2, 3 September 2001, Pages 75-77.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.